

AMENDMENTS TO THE CLAIMS

Please amend the claims as follows:

1. (Currently Amended) A vacuum deposition apparatus comprising:
a susceptor for heating a glass substrate, a portion of the susceptor providing an area used as a sliding portion on which to slide the glass substrate to a stopped position;
lift pins for supporting the glass substrate;
a robot arm for transferring the glass substrate onto the susceptor and returning the glass substrate from the susceptor, wherein the robot arm supports a portion of the glass substrate with a non-supported edge portion freely hanging over the robot arm such that as the robot arm moves in a forward direction to transfer the glass substrate onto the susceptor, the non-supported edge portion of the glass substrate slides on the sliding portion of the susceptor and is stopped by at least one stopping pin located at the stopping position; and
a groove formed in said sliding portion of the susceptor at a location of the at least one stopping pin for receiving material resulting from sliding of the glass substrate on the sliding portion of the susceptor,
wherein a length of said sliding portion, measured from said groove, is about 10 mm.

2. (Canceled)

3. (Canceled)

4. (Previously Presented) The vacuum deposition apparatus according to claim 1, wherein the susceptor is made of a quartz material.

5. (Previously Presented) The vacuum deposition apparatus according to claim 1, wherein the groove has a polygonal configuration.

6. (Previously Presented) The vacuum deposition apparatus according to claim 1, wherein a bottom face of the groove has a curved configuration.

7. (Previously Presented) The vacuum deposition apparatus according to claim 1, wherein a bottom face of the groove includes an incline plane and a perpendicular plane.

8. (Previously Presented) The vacuum deposition apparatus according to claim 1, wherein the groove has a V-shaped configuration.

9. (Canceled)

10. (Previously Presented) The vacuum deposition apparatus according to claim 4, wherein the susceptor is in direct contact with the glass substrate when the glass substrate is heated.

11. (Previously Presented) The vacuum deposition apparatus according to claim 1, wherein the non-supported portion of the glass substrate inclines with respect to a surface of the sliding portion of the susceptor when the glass substrate is slid along the sliding portion of the susceptor.

12. (Previously Presented) The vacuum deposition apparatus according to claim 1, wherein the susceptor comprises:

a first planar portion;
a second planar portion vertically above the first planar portion and horizontally contiguous with the first planar portion such that the first and second planar portions of the susceptor form a stepped-shape,

wherein the groove is formed in the second planar portion, and

wherein the glass substrate slides on the second planar portion.

13-14. (Canceled)

15. (Previously Presented) The vacuum deposition apparatus according to claim 11, wherein the incline of the non-supported edge of the glass substrate is substantially 85 degrees from a vertical when sliding the glass substrate on the sliding portion of the susceptor.

16. (Previously Presented) The vacuum deposition apparatus according to claim 1, wherein the susceptor is rectangular.